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Substitute for form 1449A/PTO

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Application Number	09/867,662
Filing Date	31 May 2001
First Named Inventor	Luc OUELLET
Art Unit	1762
Examiner Name	TALBOT, Brian K.
Attorney Docket Number	11471-US

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet 1 of 2

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document Country Code ³ Number ⁴ Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
BT		WO 97/25636	07-17-1997	Northern Telecom Ltd		
I		JP10319263A2	12-04-1998	Hitachi Cable Ltd.		
BT		JP03274272 A	12-15-1991	Matsushita Denki Sang		

Examiner

Signature

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Date

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2/28/05

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Complete if Known

Application Number

09/867,662

Filing Date

31 May 2001

First Named Inventor

Luc OUELLET

Art Unit

1762

Examiner Name

TALBOT, Brian K.

Attorney Docket Number

11471-US

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
BT		HSEIH, S.W. et al: Characteristics of Low-Temperature and Low-Energy Plasma-Enhanced Chemical Vapor Deposited SiO ₂ , August 1993, 2638-2648, Vol. 74, No 4., American Institute of Physics, Republic of China	
1		KIM, Kihong, et al.: Properties of Low Dielectric Constant Fluorinated Silicon Oxide Films Prepared by Plasma Enhanced Chemical Vapor Deposition, 1998, 369-374, Elsevier Science S.A., Baton Rouge, LA.	
BT		GRAND, G. et al.: Low-Loss PECVD Silica Channel Waveguides For Optical Communications, Electronic Letters, 6 December 1990, Vol. 26, No. 25, France	

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Signature

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